IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.:

10/583,641

Applicants:

Julien GATINEAU, et al.

Filed Internationally:

December 10, 2004

US National:

June 20, 2006

Title:

METHOD FOR CLEANING FILM-FORMING

APPARATUSES

TC/A.U.:

Unknown

Examiner:

Unknown

Docket No.:

Serie 6397

Customer No.:

40582

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner of Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In accordance with the duty of disclosure as set forth in 37 C.F.R. § 1.56, Applicants hereby submit the following information in conformance with 37 C.F.R. §§ 1.97 and 1.98. Pursuant to 37 C.F.R. § 1.98, a copy of each of the non-US patent documents cited on the attached PTO Form 1449 is enclosed.

Also enclosed is the Japanese priority document JP 20-30439.

No fee is due at this time in accordance with 37 C.F.R. § 1.97. However, the Commissioner is hereby authorized to charge any appropriate fees under 37 C.F.R. §§ 1.16, 1.17 and 1.21 that may be required by this paper, and to credit any overpayment, to Deposit Account No. 01-1375.

Application No. 10/583,641 Attorney Docket No. Serie 6397 Supplemental IDS

To assist the Examiner, the documents are listed on the attached form PTO-1449. It is respectfully requested that an Examiner-initialed copy of this form be returned to the undersigned.

Respectfully submitted,

Brandon S. Clark

Registration No. 59,020

Date: March 27, 2007

Air Liquide Intellectual Property Department 2700 Post Oak Boulevard, Suite 1800 Houston, Texas 77056 (713) 624-8787 Phone – (713) 624-8950 Fax

SUPPLEMENTAL INFORMATION DISCLOSURE CITATION

(USE SEVERAL SHEETS IF NECESSARY)

ATTY. DOCKET NO. SERIAL NO. Serie 6397 10/583,641

APPLICANT(S)

Julien GATINEAU, et al.

FILING DATE
June 20, 2006

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			U.S. PATENT	DOCUMENTS				
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date	
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	1	OTHER DOC	UMENTS (Including A	uthor, Title, Date, Pertinent	Pages, Etc.)			
	C1	Jelenkovic et al. Degradation of RuO2 thin films in hydrogen atmosphere at						
	C1 temperatures between 150 and 250 deg. C. The Institution of Electrical Engineers, Stevenage, Great Britain, January 2003							
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Examiner	/Nicole Blan/			Date Considered 03/30/2008				
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EXAMINER	R: Initia	if reference considered, whether or	not citation is in confor	nance with MPEP 609; Dra	w line through	citation if not	in conformance	and not

Form PTO-A820 Facsimile (also form PTO-1449)

PO9C/REV 03

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considered. Include copy of this form with next communication to applicant.